

# Multifield-Controlled Terahertz Hybrid Metasurface for Switches and Logic Operations

Xilai Zhao <sup>1,†</sup>, Yanan Jiao <sup>2,†</sup>, Jiangang Liang <sup>1,\*</sup>, Jing Lou <sup>1</sup>, Jing Zhang <sup>1</sup>, Jiawen Lv <sup>3</sup>, Xiaohui Du <sup>2</sup>, Lian Shen <sup>4</sup>, Bin Zheng <sup>4</sup> and Tong Cai <sup>1,4,\*</sup>

<sup>1</sup> Air and Missile Defense College, Air Force Engineering University, Xi'an 710051, China

<sup>2</sup> Department of General Surgery, First Medical Center, Chinese People's Liberation Army (PLA) General Hospital, Beijing 100024, China

<sup>3</sup> China Nuclear Engineering Consulting Corporation, Beijing 100024, China

<sup>4</sup> Interdisciplinary Center for Quantum Information, State Key Laboratory of Modern Optical Instrumentation, Zhejiang University Hangzhou Global Scientific and Technological Innovation Center, Zhejiang University, Hangzhou 310027, China

\* Correspondence: cat-liang1975@163.com (J.L.); caitong326@zju.edu.cn (T.C.)

† These authors contributed equally to this work.

## S1: Discussion of available fabrication process of the proposed device.

First, the 500 nm gold was sputtered onto a 500  $\mu\text{m}$  thickness commercially purchased sapphire substrate by an electro-beam evaporation process, followed by an etching technology to form the designed resonant cells and electrodes. Then a 500 nm thickness vanadium dioxide ( $\text{VO}_2$ ) film was grown on the sample by a radio frequency plasma-assisted oxide molecular beam epitaxy chamber. The  $\text{VO}_2$  bridges were fabricated by tailoring the  $\text{VO}_2$  layer with UV lithography technology, and the excess  $\text{VO}_2$  was removed through a reactive ion etching procedure.[1] Next, a 300 nm Ge film was thermally sputtered onto the device surface. Finally, the redundant Ge was removed using a second UV lithography and lift-off technology.[2] The proposed terahertz metasurface can be prepared by the above process.

1. Lou, J.; Xu, X.; Huang, Y.D.; Yu, Y.; Wang, J.; Fang, G.Y.; Liang, J.G.; Fan, C.H.; Chang, C. Optically Controlled Ultrafast Terahertz Metadevices with Ultralow Pump Threshold. *Small* 2021, 17, 2104275.
2. Hu, Y.Z.; Tong, M.Y.; Xu, Z.J.; Cheng, X.G.; Jiang, T. Spatiotemporal Terahertz Metasurfaces for Ultrafast All-Optical Switching with Electric-Triggered Bistability. *Laser Photonics Rev.* 2021, 15, 2000456.